

Title (en)

METHOD AND DEVICE FOR INTRODUCTION OF AIR INTO A PROCESSING CHAMBER

Title (de)

VERFAHREN UND VORRICHTUNG ZUR LUFTFÜHRUNG IN EINEM BEARBEITUNGSRAUM

Title (fr)

PROCEDE ET DISPOSITIF POUR CONDUIRE DE L'AIR DANS UN ESPACE DE TRAVAIL

Publication

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Application

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Abstract (en)

[origin: US6619901B1] An apparatus for air guidance in a processing chamber has a housing with an entrance gate and an exit gate. Inside the housing the processing chamber is embodied for filling and sealing small bottles or ampules. The processing chamber is separated from an outside region via an intermediate region. The intermediate region having a movable door by means of which manual interventions in the processing chamber can be made. The apparatus also has a ventilation system with a blower and a clean-air filter which inside the processing chamber generates a laminar air flow. By means of special air pressure ratios in the processing chamber the intermediate region the entrance gate and the exit gate, the occurrence of contamination, or its exceeding a tolerable amount, in the processing chamber (12) and the outside region is avoided.

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